## **IN THE CLAIMS**

Please amend the claims as follows:

- 1 (Currently Amended). A microphotonic device comprising:
- a flexible membrane structure that can experience strain; and
- a waveguide element formed on said <u>flexible</u> membrane structure so that when
- 4 said flexible membrane structure is strained, said waveguide element is tuned to a
- 5 selective amount.
- 2 (Currently Amended). The microphotonic device of claim 1, wherein said <u>flexible</u>
- 2 membrane structure comprises a sub-micron SiO<sub>2</sub> layer.
- 1 3 (Original). The microphotonic device of claim 1, wherein said waveguide element
- 2 comprises a microring resonator.
- 4 (Original). The microphotonic device of claim 1, wherein said waveguide element
- 2 comprises a microracetrack resonator.
- 5 (Original). The microphotonic device of claim 1, wherein said waveguide element
- 2 comprises a 1-dimensional photonic crystal.
- 6 (Original). The microphotonic device of claim 1, wherein said waveguide element
- 2 comprises a 2-dimensional photonic crystal.
- 1 7 (Original). The microphotonic device of claim 5, wherein said 1-dimensional
- 2 photonic crystal comprises holes.

- 8 (Original). The microphotonic device of claim 7, wherein said selective amount
- 2 comprises approximately 1%.
- 9 (Original). The microphotonic device of claim 3, wherein said selective amount
- 2 comprises 0.2%.
- 1 10 (Currently Amended). The microphotonic device of claim 1 further comprising at
- 2 least one piezoelectric actuator that is coupled to said\_flexible\_-membrane so as to
- 3 produce said strain.
- 1 11 (Currently Amended). A method of forming a microphotonic device comprising:
- 2 providing a flexible membrane structure that can experience strain; and
- forming a waveguide element on said <u>flexible</u> membrane structure so that when
- 4 said <u>flexible</u> membrane structure is strained said waveguide element is tuned to a
- 5 selective amount.
- 1 12 (Currently Amended). The method of claim 11, wherein said flexible membrane
- 2 structure comprises a sub-micron SiO<sub>2</sub> layer.
- 1 13 (Original). The method of claim 11, wherein said waveguide element comprises a
- 2 microring resonator.
- 1 14 (Original). The method of claim 11, wherein said waveguide element comprises a
- 2 microracetrack resonator.

- 1 15 (Original). The method of claim 11, wherein said waveguide element comprises a
- 2 1-dimensional photonic crystal.
- 1 16 (Original). The method of claim 11, wherein said waveguide element comprises a
- 2 2-dimensional photonic crystal.
- 1 17 (Original). The method of claim 15, wherein said 1-dimensional photonic crystal
- 2 comprises holes.
- 1 18 (Original). The method of claim 17, wherein said selective amount comprises
- 2 approximately 1%.
- 1 19 (Original). The method of claim 13, wherein said selective amount comprises
- 2 0.2%.
- 20 (Currently Amended). The method of claim 11 further comprising providing at least
- one piezoelectric actuator that is coupled to said <u>flexible</u> membrane so as to produce
- 3 said strain.